IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Ravi Iyer \

erial No.: 09/059,865

Filed: April 14, 1998

Assistant Commissioner

Washington, D.C. 20231

for Patents

For:

PLANARIZATION USING PLASMA

OXIDIZED AMORPHOUS SILICON

Group Art Unit: 2813

Examiner:

Nguyen, T.

Atty Docket: MICS:0015--2/FLE

93-118.02

CERTIFICATE OF TRANSMISSION AND MAILING 37 C.F.R. 1.8

I hereby certify that this correspondence is being transmitted by facsimile to the United States Patent and Trademark Office in accordance with 37 C.F.R. 1.6(d) and is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on the date below:

December 3, 1998

999999

Date

Michael G. Fletcher

Sir:

AMENDMENT

In response to the Official Action mailed on August 3, 1998, please amend the abovereferenced application as follows:

IN THE CLAIMS

Please cancel claim 1 without prejudice.

Please amend claims 18, 22, and 23 as set forth below:

TITECHNOLOGY CENTER 2800 :9 HW

18 (once amended). A method of manufacturing an integrated circuit, the method comprising the steps of: